

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)
Hidekazu MIYAIRI et al.) Group Art Unit: 1722
Serial No. 10/663,671) Examiner: Felisa Carla Hiteshew
Filed: September 17, 2003)
For: LASER APPARATUS, LASER IRRADIATION) Date: June 8, 2006
METHOD, AND MANUFACTURING METHOD
OF SEMICONDUCTOR DEVICE

INFORMATION DISCLOSURE STATEMENT

Mail Stop **Amendment**
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

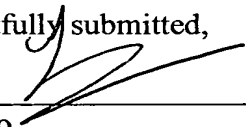
Sir:

In accordance with the duty of disclosure as set forth in 37 C.F.R. §1.56, Applicants hereby submit the following information in conformance with 37 C.F.R. §§ 1.97 and 1.98

It is requested that the accompanying PTO-1449 be considered and made of record in the above-identified application. To assist the Examiner, the documents are listed on the attached form PTO-1449. It is respectfully requested that an Examiner initial a copy of this form be returned to the undersigned.

The Commissioner is hereby authorized to charge any fees connected with this filing which may be required now, or credit any overpayment to Deposit Account No. 19-2380.

Respectfully submitted,



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